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(54) Title: IMAGING THOUSANDS OF ELECTRON BEAMS DURING WORKPIECE INSPECTION

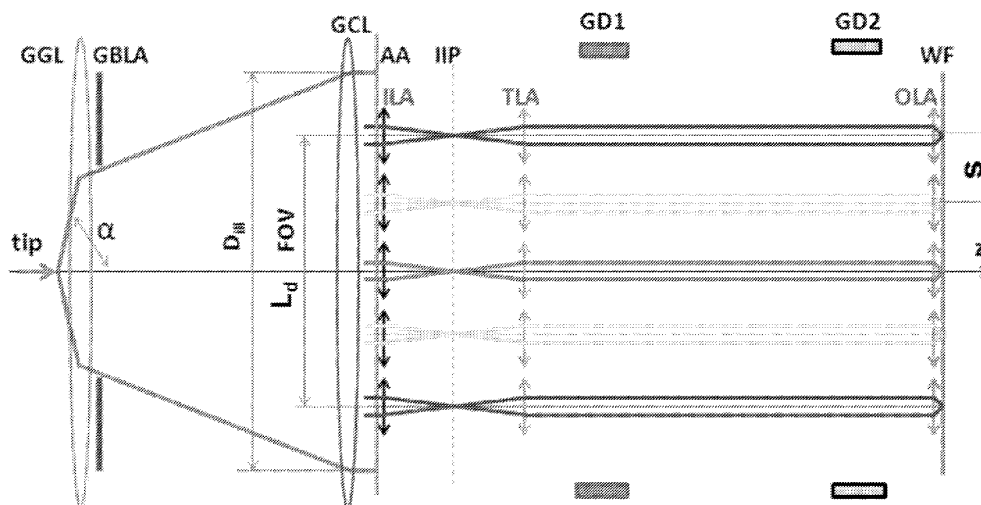


FIG. 4

(57) Abstract: Beamlets are generated from the electron beam using an aperture array downstream of the single global collimated lens. The beamlets are directed through an image lens array in a path of the beamlets downstream of the aperture array that individually focuses the beamlets onto the intermediate image plane with the image lens array. The beamlets are then directed at a workpiece on a stage using a transfer lens array downstream of the image lens array. A path of the beamlets does not include a crossover.

[Continued on next page]

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